

# PS4L Vacuum Probing System

- ◆ Dual stage vacuum system down to  $10^{-4}$  torr for wafer testing in a vacuum environment
- ◆ Semiautomatic and Automatic versions
- ◆ Modular adaptive hardware and software architecture
  - ◆ All components are interchangeable and completely field upgradeable
- ◆ Comprehensive portfolio of optional accessories and upgrades
- ◆ Easily customized to meet a variety of applications and budgets

## VACUUM SYSTEM

- ◆ Sliding Gantry system
  - ◆ Manual or programmable microscope transport
  - ◆ Ease of chamber access
- ◆ IR Blackbody
- ◆ Interchangeable chamber top accommodates probe card or manipulators
- ◆ Large load port with full visibility to test area
- ◆ High speed, high accuracy programmable stage
- ◆ Large variety of access ports available for future expansion
- ◆ Welded aluminum vacuum chamber
- ◆ Precision vacuum control enables pressure setting and recording
- ◆ Two stage pump
  - ◆ Roughing
  - ◆ Turbo Molecular Drag
- ◆ Optional thermal chuck system
  - ◆  $-60^{\circ}$  to  $200^{\circ}$  C
- ◆ Vibration Isolation Table
- ◆ Optional Air Pressure Pump

## CONTROL ELECTRONICS

- ◆ PILOT Control Software for Wafer Map, Auto Alignment and test equipment integration
- ◆ Test Equipment
  - ◆ Differential Blackbody Controller
  - ◆ Keithley 4200
- ◆ Equipment Rack
  - ◆ Manipulator motion controllers
  - ◆ Stage motion controller
  - ◆ PC Platform
    - ◆ PILOT Control Software
    - ◆ Test equipment integration software

## OPTIONAL TEST EQUIPMENT

- ◆ MSA 500 Motion Analyzer
- ◆ Black Body Systems



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